

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)
Mitsuhiro ICHIJO et al.) Confirmation No. 7738
Application No. 10/804,053) Examiner: Long Pham
Filed: March 19, 2004) Group Art Unit: 2814
For: FILM FORMATION METHOD AND)
MANUFACTURING METHOD OF)
SEMICONDUCTOR DEVICE) Date: October 26, 2007

AMENDMENT AFTER FINAL

MAIL STOP RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the final Office Action mailed August 3, 2007, Applicants respectfully request reconsideration and allowance of the above-identified application in view of the following amendments and remarks.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 14 of this paper.